

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Gabric, et. Al., *et al.*

Docket No.: INF 2006 VJ 33543 US

Serial No.: 10/586,788

Art Unit: 2893

Filed: September 2, 2008

Examiner: Nikolay K. Yushin

For: Plasma Excited Chemical Vapor Deposition Method, Silicon/Oxygen/Nitrogen-Containing-Material and Layered Assembly

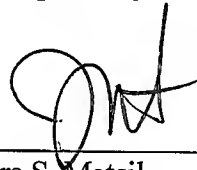
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Request For Confirmation of Information Disclosure Statement

Dear Sir:

The patent application for the above-referenced patent application was allowed on March 18, 2010. Information Disclosure Statements (copies attached) and the appropriate fees were filed by Applicants with the Amendment of September 4, 2009 and Information Disclosure Statement of November 5, 2009. However, Applicants did not receive confirmation of consideration of the Information Disclosure Statement by the Examiner with the Notice of Allowance. Applicants kindly request that the Office forward the initialed copy of the PTO/SB/08A.

Respectfully submitted,



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4/6/10

Date

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